

Initial Information Data Sheet

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Application Information

Title Line One:: METHOD FOR CONTROLLING THE MORPHOLOGY
Title Line Two:: OF DEPOSITED SILICON ON A SILICON DIOXIDE
Title Line Three:: SUBSTRATE AND SEMICONDUCTOR DEVICES
Title Line Four:: INCORPORATING SUCH DEPOSITED SILICON
Total Drawing Sheets:: 4
Formal Drawings?:: Yes
Application Type:: Utility
Docket Number:: MIO 0037 VA

Representative Information

Registration Number One:: 26,397
Registration Number Two:: 27,262
Registration Number Three:: 29,001
Registration Number Four:: 39,564
Registration Number Five:: 38,769
Registration Number Six:: 33,758
Registration Number Seven:: 42,695
Registration Number Eight:: 44,494
Registration Number Nine:: P-46,867
Registration Number Ten:: P-46,506
Registration Number Eleven:: 30,871
Registration Number Twelve:: 34,095

Continuity Information

This application is a:
> Application One:
Filing Date::

Division of
09/072,262
May 4, 1998